

	Type	Hits	Search Text	DBs	Time Stamp
16	IS&R	340	(359/201).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 12:32
17	IS&R	186	(359/202).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 12:43
18	IS&R	579	(359/212).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 13:15
19	IS&R	175	(359/213).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 13:21
20	IS&R	253	(359/214).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 13:32
21	IS&R	154	(359/220).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 13:34
22	IS&R	283	(359/221).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 13:41
23	IS&R	510	(359/223).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 14:22
24	IS&R	407	(359/224).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 15:07
25	IS&R	140	(359/225).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 15:10
26	IS&R	384	(359/850).CCLS.	USPAT; US-PGPUB; EPO	2002/10/02 15:18
27	BRS	3056	"MEMS"	USPAT; US-PGPUB; EPO; JPO	2002/10/02 15:18
28	BRS	862	"MEMS" and polysilicon	USPAT; US-PGPUB; EPO; JPO	2002/10/02 15:32
29	IS&R	2	((("5646928") or ("6074890")).PN.	USPAT	2002/10/02 15:32

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	7324	(low adj2 pressure) WITH (chemical adj vapor adj deposition)	USPAT	2002/10/04 14:30
2	BRS	L2	4950	1 and polysilicon	USPAT	2002/10/04 14:30
3	BRS	L3	7859	"LPCVD"	USPAT	2002/10/04 14:30
4	BRS	L4	5564	3 and polysilicon	USPAT	2002/10/04 14:31
5	BRS	L5	77	4 and "MEMS"	USPAT	2002/10/04 14:32
6	BRS	L6	2573	"LPCVD" WITH polysilicon	USPAT	2002/10/04 14:33
7	BRS	L7	45	6 and MEMS	USPAT	2002/10/04 14:33